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CENTRAL FAX CENTER**

Patent

FEB 05 2005Customer No.: 31561
Application No.: 10/064,703
Docket No. 9458-US-PA**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Applicant : Lin
Application No. : 10/064,703
Filed : August 8, 2002
For : METHOD FOR DEPOSITING THIN FILM USING
PLASMA CHEMICAL VAPOR DEPOSITION
Art Unit : 1762
Examiner : MEEKS, TIMOTHY HOWARD

TRANSMITTAL LETTER

002-1-703-872-9306

(Via fax: 1+2+11 pages)

ASSISTANT COMMISSIONER FOR PATENTS
Arlington, VA22202

Dear Sir,

In response to the Office Action dated November 15, 2004(paper no. 20041108), please find the relevant papers as follows:

- ☒ Request for Continued Examination in (2) pages;
☒ Preliminary Amendment in (11) pages.

Thank you for your assistance in the subject matter. If you have any questions, please feel free to contact me.

Respectfully Submitted,
JIANQ CHYUN Intellectual Property Office

Date:

February 5, 2005

By:

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